

Docket No.: GR 96 P 8091 D2

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Michael Kelly et al.  
Div. of Applic. No. : 10/324,848, filed December 20, 2002  
Div. filed : September 29, 2003  
Title : Method of Producing a Light-Emitting Diode  
Examiner : William D. Coleman                      Group Art Unit: 2823

INFORMATION DISCLOSURE STATEMENT

Hon. Commissioner for Patents;  
Alexandria, VA 22313-1450

S i r :

In accordance with 37 C.F.R. 1.98, the following patents and/or publications are cited herewith:

U.S. Patent No. 4,448,636 (Baber), dated May 15, 1984;

U.S. Patent No. 4,883,561 (Gmitter et al.), dated November 28, 1989;

German Published, Non-Prosecuted Patent Application No. DE 35 08 469 A1 (Mück et al.), dated September 11, 1986;

Published, European Patent Application No. EP 0 718 885 A2 (Gorowitz et al.), dated June 26, 1996;

M.K. Kelly et al.: "Optical Patterning of GaN films", Appl. Physics, Letter 69 (12), September 16, 1996, pp. 1749-51;

Eli Yablonovitch et al.: "Extreme Selectivity in the Lift-Off of Epitaxial GaAs films", Appl. Physics Letter 51 (26), December 28, 1987, pp. 2222-24;

R. Groh et al.: "On the Thermal Decomposition of GaN in Vacuum", pp. 353-57;

Yasua Morimoto: "Few Characteristics of Epitaxial GaN-Etching and Thermal Decomposition", J. Electrochemical Society: Solid State Science and Technology, October 1974, pp. 1383-84;

R.T. Leonard et al.: "Photoassisted Dry Etching of GaN", Appl. Physics , Letter 68, February 5, 1996, pp. 794-96;

Young-Feng Lu et al.: "Laser-Induced Dry Lift-Off Process", Jpn. J. Appl. Physics, Volume 34, 1995, pp. 1669-70;

Young-Feng Lu et al.: "Excimer-Laser Removal of SiO<sub>2</sub> Patterns from GaAs Substrates", Jpn. Appl. Physics, Volume 33, 1994, pp. 324-27.

The above-mentioned references were cited in an *Information Disclosure Statement* dated April 1, 1999, in grandparent application No. 09/283,907.

C.R. Miskys et al.: "MOCVD-Epitaxy on Free-Standing HVPE-GaN Substrates", Phys. Stat. Sol. (a) 176, 443 (1999), pp. 443-46;

L. Tsakalakos et al.: "Epitaxial Ferroelectric (Pb, La)(Zr, Ti)O<sub>3</sub> Thin Films on Stainless Steel By Excimer Laser Liftoff", Applied Physics Letters, Volume 76, No. 2, January 10, 2000, pp. 227-29.

The above-mentioned references were cited in an *Information Disclosure Statement* dated June 13, 2000, in grandparent application No. 09/283,907.

U.S. Patent No. 6,071,795 (Cheung et al.), dated June 6, 2000;

Published, European Patent Application No. EP 0 987 741 A1 (Wang et al.), dated March 22, 2000.

The above-mentioned references were cited in an *Information Disclosure Statement* dated June 22, 2000, in grandparent application No. 09/283,907.

U.S. Patent No. 3,808,550 (Ashkin), dated April 1994;

U.S. Patent No. 5,985,687 (Bowers et al.), dated November 1999;

U.S. Patent No. 6,159,824 (Henley et al.), dated December 2000.

The above-mentioned references were cited in an Office Action dated October 3, 2001, in grandparent application No. 09/283,907.

U.S. Patent No. 5,559,043 (Bruehl), dated September 1996.

The above-mentioned reference was cited in an Office Action dated April 18, 2002, in grandparent application No. 09/283,907.

U.S. Patent No. 4,846,931 (Gmitter et al.), dated July 11, 1989;

U.S. Patent No. 5,465,009 (Drabik et al.), dated November 7, 1995.

The above-mentioned references were filed in an *Information Disclosure Statement* filed September 8, 2003, in parent application No. 10/324,848.

Respectfully submitted,



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For Applicants

Date: September 29, 2003

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| FORM PTO-1449 (SUBSTITUTE)<br><br>U.S. DEPARTMENT OF COMMERCE<br>PATENT AND TRADEMARK OFFICE<br><br>INFORMATION DISCLOSURE<br>STATEMENT BY APPLICANT<br>(37 CFR 1.98(b))  |   |   |       | Attorney Docket No.: GR 96 P 8091 D2      Divisional of Applic. No. 10/324,848<br><br>Applicant<br>Michael Kelly et al.<br><br>Filing Date of Divisional September 29, 2003      Group Art Unit 2823 |       |              |                     |
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| EXAMINER<br>INITIALS  |   | PATENT NO.  | DATE  | PATENTEE   | CLASS | SUB<br>CLASS | FILING<br>DATE      |
|   | A | 3,808,550   | 04/94 | Ashkin   |       |              |                     |
|   | B | 4,448,636   | 05/84 | Baber  |       |              |                     |
|   | C | 4,846,931   | 07/89 | Gmitter et al.   |       |              |                     |
|   | D | 4,883,561   | 11/89 | Gmitter et al.   |       |              |                     |
|   | E | 5,465,009   | 11/95 | Drabik et al.  |       |              |                     |
|   | F | 5,559,043   | 09/96 | Bruel  |       |              |                     |
|   | G | 5,985,687   | 11/99 | Bowers et al.  |       |              |                     |
|   | H | 6,071,795   | 06/00 | Cheung et al.  |       |              |                     |
|   | I | 6,159,824   | 12/00 | Henley et al.  |       |              |                     |
| FOREIGN PATENT DOCUMENT   |   |   |       |  |       |              |                     |
|   |   | DOCUMENT NO.  | DATE  | COUNTRY  | CLASS | SUB<br>CLASS | TRANSL.<br>YES   NO |
|   | J | DE 35 08 469 A1   | 09/86 | Germany  |       |              |                     |
|   | K | EP 0 718 885 A2   | 06/96 | Europe   |       |              |                     |
|   | L | EP 0 987 741 A1   | 03/00 | Europe   |       |              |                     |
|   | M |   |       |  |       |              |                     |
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| OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.)  |   |   |       |  |       |              |                     |
|   |   | M.K. Kelly et al.: "Optical Patterning of GaN films", Appl. Physics, Letter 69 (12), September 16, 1996, pp. 1749-51.                                 |       |  |       |              |                     |
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| EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant. |   |   |       |  |       |              |                     |

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|   |   | L. Tsakalakos et al.: „Epitaxial Ferroelectric (Pb, La)(Zr, Ti)O <sub>3</sub> Thin Films on Stainless Steel By Excimer Laser Liftoff“, Applied Physics Letters, Volume 76, No. 2, January 10, 2000, pp. 227-29. |      |   |       |              |                     |
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